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Kaneko

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(54) **COATING AND DEVELOPING APPARATUS,
METHOD OF OPERATING THE SAME AND
STORAGE MEDIUM**

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(52) **U.S. Cl.**

CPC **G03F 7/2035** (2013.01); **G03F 7/3042**
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(58) **Field of Classification Search**

USPC 396/611
See application file for complete search history.

ABSTRACT

A coating and developing apparatus includes: first and second transfer mechanisms for transferring a substrate from a first mount module to a second mount module, one of the first and second transfer mechanisms being selected each time when the substrate transfer should be performed; first and second processing modules for performing substrate processing, for which the transfer of substrates is performed by the first and second transfer mechanisms, respectively; and a control unit. The control unit controls the transfer mechanisms for the substrate transfer by determining a delay time, representing a delay caused by the transfer of the substrate to the second mount module to the timing of transfer of a substrate from the first/second processing module, in regard to each of the first and second transfer mechanisms and selecting one of the first and second transfer mechanisms whose delay time is the shortest.

9 Claims, 15 Drawing Sheets

